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ABSTRACT

In a wafer transfer system wherein a wafer transfer robot linearly reciprocates by a linear motor, dust is prevented from
5 adhering to a wafer.

A fixed base 9, on which the secondary side 11 of a linear motor M for linearly reciprocating a wafer transfer robot R is mounted, is mounted on the system body 1 of a wafer transfer system A in lateral directions and in vertical directions, so that dust
10 dropping in accordance with the flow of clean air K from a clean air supply system 4 is directly sucked into an exhaust fan 5, which is provided on the bottom portion 1c of the system body 1, to be exhausted without being deposited on the top face of the fixed base 9 and the secondary side 11.

RECORDED IN U.S. PATENT OFFICE